Docket No.

206342US2

IN RE APPLICATION OF:

Toshifumi NAGAIWA, et al.

SERIAL NO:

09/840,178

FILED:

April 24, 2001

FOR:

WORKTABLE DEVICE AND PLASMA PROCESSING APPARATUS FOR SEMICONDUCTOR

PROCESS

ASSISTANT COMMISSIONER FOR PATENTS WASHINGTON, D.C. 20231

SIR:

Transmitted herewith is an amendment in the above-identified application.

■ No additional fee is required

Small entity status of this application under 37 C.F.R. §1.9 and §1.27 is claimed.

Marked-up Copy, Letter to Official Draftsman, Drawings (1 Sheet) Additional documents filed herewith:

The Fee has been calculated as shown below:

CLAIMS	CLAIMS REMAINING		HIGHEST NUMBER PREVIOUSLY PAID	NO. EXTRA CLAIMS		RATE		CALCULATIONS
TOTAL	18	MINUS	20	0	х	\$18	=	\$0.00
INDEPENDENT	4	MINUS	3	1	x	\$84	=	\$84.00
		☐ MULTIPLE DEPENDENT CLAIMS		CLAIMS	+	\$280	=	\$0.00
TOTAL OF ABOVE CALCULATION					NS	\$84.00		
☐ Reduction by 50% for filing by Small Entity							\$0.00	
Recordation of Assignment					+	\$40	=	\$0.00
						TOT	AL	\$84.00

A check in the amount of \$84.00 is attached.

- Please charge any additional Fees for the papers being filed herewith and for which no check is enclosed herewith, or credit any overpayment to deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.
- ☑ If these papers are not considered timely filed by the Patent and Trademark Office, then a petition is hereby made under 37 C.F.R. §1.136, and any additional fees required under 37 C.F.R. §1.136 for any necessary extension of time may be charged to Deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

22850

Customer Number 22850 Tel. (703) 413-3000 Fax. (703) 413-2220 (OSMMN 10/01) GJM/CES/MAJ I:\ATTY\CES\206342US.PTO.DOC OBLON, SPIVAK, McCLELLAND,

Gregory J. Maier

Registration No. 25,599

Carl E. Schlier

34,426 Registration No.

SEP 2 4 2002 TC 1700

DOCKET NO.: 206342US2



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IN RE APPLICATION OF

TOSHIFUMI NAGAIWA, ET AL.

: EXAMINER: 1763

SERIAL NO: 09/840,178

FILED: APRIL 24, 2001

: GROUP ART UNIT: KACKAR, R

FOR:

WORKTABLE DEVICE AND PLASMA PROCESSING APPARATUS FOR

SEMICONDUCTOR PROCESS

LETTER REQUESTING APPROVAL OF DRAWING CHANGES

ASSISTANT COMMISSIONER FOR PATENTS WASHINGTON, DC 20231

SIR:

Please review for approval the proposed change to the Formal Drawings shown in **RED** on the attached photocopy of the drawings (1 sheet).

Once this change has been reviewed and approved by the Examiner in charge of this case, instructions for its implementation will be forwarded to an approved bonded draftsman.

> Respectfully submitted, OBLON, SPIVAK, McCLELLAND, MAIER & NEUSTADT, P.C.

Gregory J. Maier Registration No: 25,599 Attorney of Record Carl E. Schlier

Registration No. 34,426

(703) 413-3000

Fax: (703) 412-2220

SEP 2 4 2002